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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

First Named

Inventor : Benjamin Y.H. Liu et al.

Appln. No.: 10/769,011

Filed : January 30, 2004

For : HIGH-PERFORMANCE AND MULTI-
LIQUID-PRECURSOR VAPORIZATION
IN SEMICONDUCTOR THIN FILM
DEPOSITION

Group Art Unit: 1762

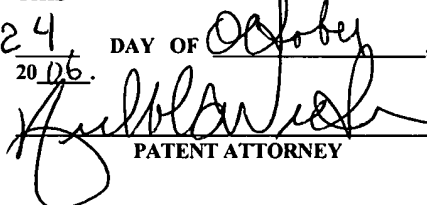
Examiner: Stouffer, Kelly

Docket No.: M419.12-0043

RESPONSE

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

I HEREBY CERTIFY THAT THIS PAPER IS
BEING SENT BY U.S. MAIL, FIRST CLASS,
TO THE COMMISSIONER FOR PATENTS,
P.O. BOX 1450, ALEXANDRIA, VA 22313-1450,
THIS

24 DAY OF October
2006.

PATENT ATTORNEY

Sir:

This is in response to the Office Action mailed on September 28, 2006. The
election of inventions is contained in this Response.